

# **11th Asia Pacific Conference on Plasma Science and Technology (APCPST) and 25th Symposium on Plasma Science for Materials 2012 (SPSM)**

**Journal of Physics: Conference Series Volume 441**

**Kyoto, Japan  
2-5 October 2012**

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**ISBN: 978-1-62748-673-6  
ISSN: 1742-6588**

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